

L Number	Hits	Search Text	DB	Time stamp
1	89661	(etch\$3 or remov\$3) same (copper or "cu")	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2002/11/18 11:42
2	96544	(etch\$3 or remov\$3 or mill\$3) same (copper or "cu")	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2002/11/18 11:46
3	12983	(halogen or iodine) same (copper or "cu")	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2002/11/18 11:47
4	2357	((etch\$3 or remov\$3 or mill\$3) same (copper or "cu")) and ((halogen or iodine) same (copper or "cu"))	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2002/11/18 11:47
5	613	((etch\$3 or remov\$3 or mill\$3) same (copper or "cu")) and ((halogen or iodine) same (copper or "cu"))) and (reaction near product)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2002/11/18 11:51
6	0	((etch\$3 or remov\$3 or mill\$3) same (copper or "cu")) and ((halogen or iodine) same (copper or "cu"))) and (reaction near product)) and (focused near ion near beam or "FIB")	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2002/11/18 12:03
7	4	((etch\$3 or remov\$3 or mill\$3) same (copper or "cu")) and ((halogen or iodine) same (copper or "cu"))) and (focused near ion near beam or "FIB")	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2002/11/18 14:19
8	15	((etch\$3 or remov\$3 or mill\$3) same (copper or "cu")) and ((halogen or iodine) same (copper or "cu"))) and (reaction near product)) and (ion near beam )	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2002/11/18 12:03
9	7	((etch\$3 or remov\$3 or mill\$3) same (copper or "cu")) and ((halogen or iodine) same (copper or "cu"))) and (reaction near product)) and (ion near beam )) and @pd<20010622	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2002/11/18 12:05
10	19	(focused near ion near beam) same (vaporiz\$3)	USPAT; US-PGPUB	2002/11/18 14:19
11	25	(focused near ion near beam) same ((remov\$3 or mill\$3 or etch\$3) same copper)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2002/11/18 13:00
12	25	((focused near ion near beam) same ((remov\$3 or mill\$3 or etch\$3) same copper)) and 2pd<20010622	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2002/11/18 13:02
13	13	((focused near ion near beam) same ((remov\$3 or mill\$3 or etch\$3) same copper)) and @pd<20010622	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2002/11/18 13:02
22	0	(copper near iodine or copper near chloride) same (focused near ion near beam or "FIB")	USPAT; US-PGPUB	2002/11/18 14:16

23	0	(copper near iodine) same (focused near ion near beam or "FIB")	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2002/11/18 14:16
24	43	((etch\$3 or remov\$3 or mill\$3) same (copper or "cu")) and ((halogen or iodine) same (copper or "cu")) and (ion near beam or "FIB")	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2002/11/18 14:21
25	1	((etch\$3 or remov\$3 or mill\$3) same (copper or "cu")) and ((halogen or iodine) same (copper or "cu")) and (ion near beam or "FIB")) and vaporiz\$3	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2002/11/18 14:20
26	23	((etch\$3 or remov\$3 or mill\$3) same (copper or "cu")) and ((halogen or iodine) same (copper or "cu")) and (ion near beam or "FIB")) and @pd<20010622	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2002/11/18 14:24